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## INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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|-------|---|----|---|
| Sheet | 1 | of | 1 |
|-------|---|----|---|

**Complete if Kn wn**

|                        |                  |
|------------------------|------------------|
| Application Number     | To Be Assigned   |
| Filing Date            | Herewith         |
| First Named Inventor   | Eric Prophet     |
| Group Art Unit         | Not Yet Assigned |
| Examiner Name          | Not Yet Assigned |
| Attorney Docket Number | 269/132          |

jc997 U.S. PTO

10/072656



## U.S. PATENT DOCUMENTS

[illegible]

#### OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS

| Examiner Initials * | Cite No. <sup>1</sup> | Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published. | T <sup>2</sup> |
|---------------------|-----------------------|---|----------------|
| Loke                | AB                    | NIELS TAS, TONNY SONNENBERG, HENRI JANSEN, ROB LEGTENBERG, MIKO ELWENSPOEK, <i>Stiction in Surface Micromachining</i> , 1996, Pages 385-397, IOP Publishing Ltd., United Kingdom  |                |
| Loke                | AC                    | TAKESHI ABE, MICHAEL L. REED, <i>Control of Liquid Bridging Induced Stiction of Micromechanical Structures</i> , 1996, Pages 213-217, IOP Publishing Ltd., United Kingdom   |                |
|                     |                       |   |                |
|                     |                       |   |                |

**Examiner  
Signature**

Loke

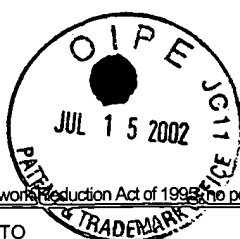
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4/25/03

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PTO/SB/08A (10-01)

Approved for use through 10/31/2002. OMB 0651-0031

U.S. Patent and Trademark Office: U.S. DEPARTMENT OF COMMERCE

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**INFORMATION DISCLOSURE  
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Sheet 1

of

2

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|                        |                  |
|------------------------|------------------|
| Application Number     | 10/072,656       |
| Filing Date            | February 7, 2002 |
| First Named Inventor   | Eric Prophet     |
| Group Art Unit         | 2811             |
| Examiner Name          | Not Yet Assigned |
| Attorney Docket Number | 269/132          |

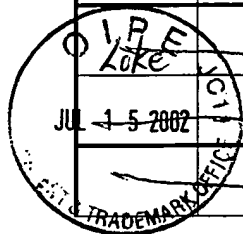
**U.S. PATENT DOCUMENTS**

| Examiner<br>Initials * | Cite<br>No. <sup>1</sup> | Document Number                            | Publication Date<br>MM-DD-YYYY | Name of Patentee or Applicant of<br>Cited Document | Pages, Columns, Lines, Where Relevant<br>Passages or Relevant<br>Figures Appear |
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| OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS |                       |   |                |
|--|-----------------------|---|----------------|
| Examiner Initials *                                | Cite No. <sup>1</sup> | Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published. | T <sup>2</sup> |
|  |                       | TAS, N. et al., Side-Wall Spacers for Stiction Reduction in Surface Micromachined Mechanisms  |                |
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|                    |             |                 |                |
|--------------------|-------------|-----------------|----------------|
| Examiner Signature | <i>Loke</i> | Date Considered | <i>4/25/03</i> |
|--------------------|-------------|-----------------|----------------|

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